

METHOD FOR FABRICATING A MICROELECTROMECHANICAL SYSTEM
(MEMS) DEVICE USING A PRE-PATTERNED SUBSTRATE

ABSTRACT OF THE INVENTION

A method for fabricating MEMS structure includes etching a recess in an upper surface of a substrate that is bonded to a wafer that ultimately forms the MEMS structure. Accordingly, once the etching processes of the wafer are completed, the recess facilitates the release of an internal movable structure within the fabricated MEMS structure without the use of a separate sacrificial material.

4633581_1.DOC

09/843 563